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METZ LEWIS
ATTORNEYS AT LAW

FACSIMILE COVER SHEET

Date: November 1, 2004

PLEASE DELIVER THE FOLLOWING FACSIMILE TRANSMISSION TO:

Name: USPTO

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Fax No.: (703) 872-9306

From: Barry I. Friedman, Esq.

Re: Serial No. 09/839,763

Pages: 4 (including cover sheet)

Message:

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Patty Boss

at 412.918.1107

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Attorney Docket No.: 1382/005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Group Art Unit 1763 : PATENT APPLICATION NOV 01 2004

Examiner P. Hassanzadeh :

In re application of : APPARATUS FOR ETCHING
SEMICONDUCTOR SAMPLES AND
LEBOUITZ ET AL. : A SOURCE FOR PROVIDING A GAS
BY SUBLIMATION THERETO

Serial No. 09/839,763 :

Filed April 20, 2001 :

REQUEST FOR CORRECTION

Pittsburgh, Pennsylvania 15222

November 1, 2004

Commissioner for Patents
P.O. Box 1450
Alexandria VA 22313-1450

Sir:

Applicants respectfully request the correction of the following typographical errors in the above-referenced application prior to printing of the issued patent:

<u>CERTIFICATE OF FACSIMILE TRANSMISSION</u>	
I hereby certify that this correspondence is being facsimile transmitted to the Patent and Trademark Office fax number (703) 872-9306 on the date shown below:	
November 1, 2004	_____
Date of Deposit	_____
Barry L. Friedman, Esq.	_____
Name of Person Signing	_____
	_____
Signature	_____

In the Title of the Invention:

Please replace the title of the invention with the following to correct a typographical error:

APPARATUS FOR ETCHING SEMICONDUCTOR SAMPLES AND A SOURCE FOR PROVIDING A GAS BY ~~SUBLIMATION~~ SUBLIMATION THERETO

In the Specification:

Please replace the paragraph beginning on Page 1, Line 12 with the following to correct typographical errors:

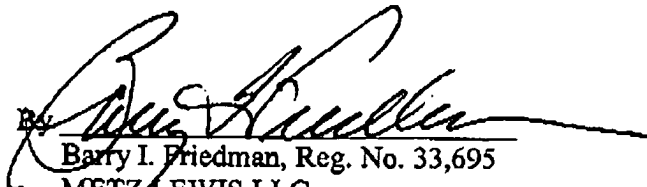
The present invention relates to an apparatus for etching semiconductor samples. More particularly, the present invention relates to an apparatus for etching semiconductor samples having a variable volume expansion chamber and to an apparatus having two or more fixed volume expansion chambers, wherein either apparatus may include an apparatus for detecting the end point of the etching process. The present invention also relates to an improved source for providing a gas by ~~sublimination~~ sublimation, in particular a source for providing a gas by ~~sublimination~~ sublimation to an apparatus described herein.

REMARKS

Notice of Allowance of the above-referenced patent application was issued by the United States Patent and Trademark Office on January 8, 2004. In response, Applicants filed formal drawings on January 21, 2004 and forwarded their Issue Fee payment on March 22, 2004.

Applicants have since discovered typographical errors in the title of the application and in the first page of the specification which they would like to correct prior to printing. Applicants respectfully request that the above-noted corrections be made prior to the grant of Letters Patent.

Respectfully submitted,


By Barry I. Friedman, Reg. No. 33,695
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